Electronic Patent Application Fee Transmittal								
Application Number:								
Filing Date:								
Title of Invention:	Method of Forming Thin SGOI Wafers with High Relaxation and Low Stacking Fault Defect Density							
First Named Inventor:	Huajie Chen							
Filer:	Yuanmin Cai							
Attorney Docket Number:	FIS920030342US1							
Filed as Large Entity								
U.S. National Stage under 35 USC 371 Filing Fees								
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)			
Basic Filing:								
National Stage Fee		1631	1	300	300			
Natl Stage Search - U.S. as IPE or ISA		1640	1	0	0			
National Stage Exam Fee - U.S. was IPEA		1643	1	0	0			
Pages:								
Claims:								
Miscellaneous-Filing:								
Petition:								
Patent-Appeals-and-Interference:								

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Miscellaneous:				
	Tota	al in USC	O (\$)	300